

TRANSMITTAL OF INFORMATION DISCLOSURE STATEMENT
Under 37 CFR 1.97(b), (c), or (d)

Docket No.
7938/ETCH/SILICON

In re Application of: **Davis, et al.**

Serial No.
10/628,001

Filing Date
July 25, 2003

Examiner

Group Art Unit

Title: **METHOD FOR AUTOMATIC DETERMINATION OF SEMICONDUCTOR PLASMA CHAMBER
 MAPPING AND SOURCE OF FAULT BY COMPREHENSIVE PLASMA MONITORING**

Address to:
**Commissioner for Patents
 Alexandria, VA 22313-1450**



37 CFR 1.97(b)

1. The Information Disclosure Statement submitted herewith is being filed within three months of the filing of a national application other than a continued prosecution application under 37 CFR 1.53(d); within three months of the date of entry of the national stage as set forth in 37 CFR 1.491 in an international application; before the mailing of a first Office Action on the merits; or before the mailing of a first Office Action after the filing of a request for continued examination under 37 CFR 1.114.

37 CFR 1.97(c)

2. The Information Disclosure Statement submitted herewith is being filed after the period specified in 37 CFR 1.97(b), but prior to the mailing date of a Final Action under 37 CFR 1.113, a Notice of Allowance under 37 CFR 1.311, or an Action that otherwise closes prosecution in the application, and is accompanied by the statement or fee as indicated below.

37 CFR 1.97(d)

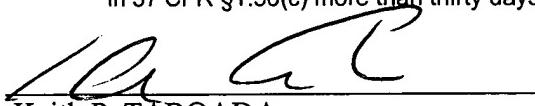
3. The Information Disclosure Statement submitted herewith is being filed after the period specified in 37 CFR 1.97(c), but on or before payment of the issue fee and is accompanied by the statement and fee as indicated below.

Required Statements and/or Fees Under 37 CFR 1.97(c) or (d)

- Each item of information contained in the accompanying Information Disclosure Statement was first cited in any communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of the Information Disclosure Statement. (37 CFR 1.97(e)(1))
- No item of information in the accompanying Information Disclosure Statement was cited in a communication from a foreign patent office in a counterpart foreign application, and, to the knowledge of the undersigned person, after making reasonable inquiry, no item of information contained in the accompanying Information Disclosure Statement was known to any individual designated in 37 CFR 1.56(c) more than three months prior to the filing of the Information Disclosure Statement. (37 CFR 1.97(e)(2))
- The fee set forth in 37 CFR 1.17(p). Please credit any overpayment or charge any insufficiencies to deposit account number 20-0782.

37 CFR §1.704(d)

4. Each item of information in the accompanying Information Disclosure Statement was cited in a communication from a foreign patent office in a counterpart application and this communication was not received by any individual designated in 37 CFR §1.56(c) more than thirty days prior to the filing of the Information Disclosure Statement.


Keith P. TABOADA

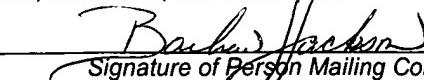
Reg. No. 45,150

Moser, Patterson & Sheridan, LLP
Attorneys at Law
595 Shrewsbury Avenue, Suite 100
Shrewsbury, New Jersey 07702
732-530-9404

Dated: Oct 28, 2003

Certificate of Mailing by First Class Mail

I certify that this document is being deposited on 10-28-2003 with the U.S. Postal Service as first class mail under 37 CFR §1.8 and is addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450



Signature of Person Mailing Correspondence

Barbara J. Jackson

Typed or Printed Name of Person Mailing Correspondence

U.S. Department of Commerce, Patent and Trademark Office (PTO Form 1449 modified)				Docket No. 7938/ETCH/SILICON	Serial No. 10/628,001			
INFORMATION DISCLOSURE STATEMENT BY APPLICANT <i>OCT 30 2003</i>				Applicant Davis, et al.	Confirmation No.:			
(Use several sheets if necessary)				Filing Date 07/25/03	Group			
Examiner								
U.S. Patent Documents								
*Examiner Initial		Document Number	Issue Date	Applicant(s) Name	Class	Subclass	Filing Date If Appropriate	
	A1	6,419,846	07/16/2002	Toprac et al.	216	60		
	A2	6,521,080	02/18/2003	Balasubramhanya et al.	156	345.24		
	A3							
	A4							
	A5							
	A6							
	A7							
	A8							
	A9							
	A10							
Foreign Patent Documents								
*Examiner Initial		Document Number	Date	Country	Class	Subclass	Translation	
							YES	NO
	B1						<input type="checkbox"/>	<input type="checkbox"/>
	B2						<input type="checkbox"/>	<input type="checkbox"/>
	B3						<input type="checkbox"/>	<input type="checkbox"/>
	B4						<input type="checkbox"/>	<input type="checkbox"/>
	B5						<input type="checkbox"/>	<input type="checkbox"/>
OTHER ART								
*Examiner Initial		Including Author, Title, Date, Pertinent Pages, Etc.						
	C1	Yue, et al., "Plasma etching endpoint detection using multiple wavelengths for small open-area wafers," J. Vac. Sci. Technol. A, 19(1), Jan/Feb 2001, 66-75						
	C2							
	C3							
Examiner				Date Considered				
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.								